

**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**LISTING OF CLAIMS:**

1. (Currently Amended) A CVD apparatus comprising:
  - a vacuum vessel separated into two chambers;
  - the first one of the two chambers containing a radio-frequency electrode;
  - the second one of the two chamber containing a substrate support mechanism for mounting a substrate;
  - wherein said vacuum vessel is separated into the two chambers by an electrically conductive partitioning section, said partitioning section comprising:
    - an outer perimeter;
    - a plurality of through-holes to allow communication between the first chamber and the second chamber;
    - an interior space for receiving a reactive gas, the interior space separated from the first chamber and communicating with the second chamber through a plurality of diffusion holes;
    - a heater for heating the electrically conductive partitioning section, and
    - an electrically conductive spiral shield that is able to withstand high temperatures;
  - wherein the partitioning section is mounted to the vacuum vessel ~~by means of a mounting screw such that the outer perimeter of the partitioning section does not directly contact the vacuum vessel~~, and the electrically conductive spiral shield is

arranged such that electrical contact between the partitioning section and the vacuum vessel is achieved through said spiral shield.

2. (Canceled)

3. (Currently Amended) A CVD apparatus comprising:

a vacuum vessel separated into two chambers;

at least one radio-frequency electrode contained in a first one of said two chambers;

a substrate support mechanism contained in the second one of said two chambers;

an electrically conductive partition section having an outer perimeter;

an electrically conductive spiral shield that is able to withstand high temperatures; and

wherein said vacuum vessel is separated into two chambers by said electrically conductive partition section which is mounted to said vacuum vessel ~~by means of a mounting screw such that the outer perimeter of the partitioning section does not directly contact the vacuum vessel~~, and the electrically conductive spiral shield is arranged such that electrical contact between the partitioning section and the vacuum vessel is achieved through said spiral shield.

4. (Previously Presented) The apparatus of claim 1, wherein the heater is adapted to heat the partitioning section to at least 100°C.

5. (Previously Presented) The apparatus of claim 1, wherein the heater is adapted to heat the partitioning section to at least 200°C.

6. (Previously Presented) The apparatus of claim 1, wherein the heater is adapted to heat the partitioning section to a temperature at which the adsorption of fluorine onto an inner circumferential face of the through-holes and a surface of the partitioning section is suppressed.

7. (New) The apparatus of claim 1, further comprising a fixing part extending into an interior of the vacuum vessel from a wall thereof and the partitioning section is attached to the fixing part.

8. (New) The apparatus of claim 3, further comprising a fixing part extending into an interior of the vacuum vessel from a wall thereof and the partition section is attached to the fixing part.

9. (New) The apparatus of claim 1, wherein the electrically conductive spiral shield is able to withstand high temperatures of at least about 100° C.

10. (New) The apparatus of claim 3, wherein the electrically conductive spiral shield is able to withstand high temperatures of at least about 100° C.